That which is claimed is:

1. A method for use during manufacture of a flat-panel display from a glass substrate comprising:

providing a vacuum processing system having:

a transfer chamber adapted to transfer the substrate under vacuum conditions, the transfer chamber having a sidewall with a plurality of facets formed therein;

a domed lid mounted on the transfer chamber and adapted to form an airtight seal with the transfer chamber;

at least a first process chamber coupled to the transfer chamber via a first of the plurality of facets, wherein the first facet is adapted to provide access to and isolation between the transfer chamber and the first process chamber; and

at least a first load lock chamber coupled to the transfer chamber via a second one of the plurality of facets, wherein the second facet provides access to and isolation between the transfer chamber and the first load lock chamber; and

employing the vacuum processing system during manufacture a flat-panel display from the substrate.

2. The method of claim 1 wherein employing the vacuum processing system during manufacture of a flat-panel display includes:

loading the substrate into the first load lock chamber;

reducing the pressure in the first load lock chamber to substantially match a pressure in the transfer chamber; and

transferring the substrate from the load lock chamber to the first processing chamber.

3. The method of claim 2 further comprising cooling the substrate in the transfer chamber.

4. The method of claim 1 further comprising viewing the substrate via one or more windows formed within the domed lid.

5. The method of claim 4 wherein the one or more windows are oriented perpendicularly

relative to the substrate.

6. The method of claim 1 further comprising:

coupling a sensor internally on the lid; and

employing the sensor to determine a position of the substrate within the transfer chamber.

7. The method of claim 6 further comprising correcting the position of the substrate.